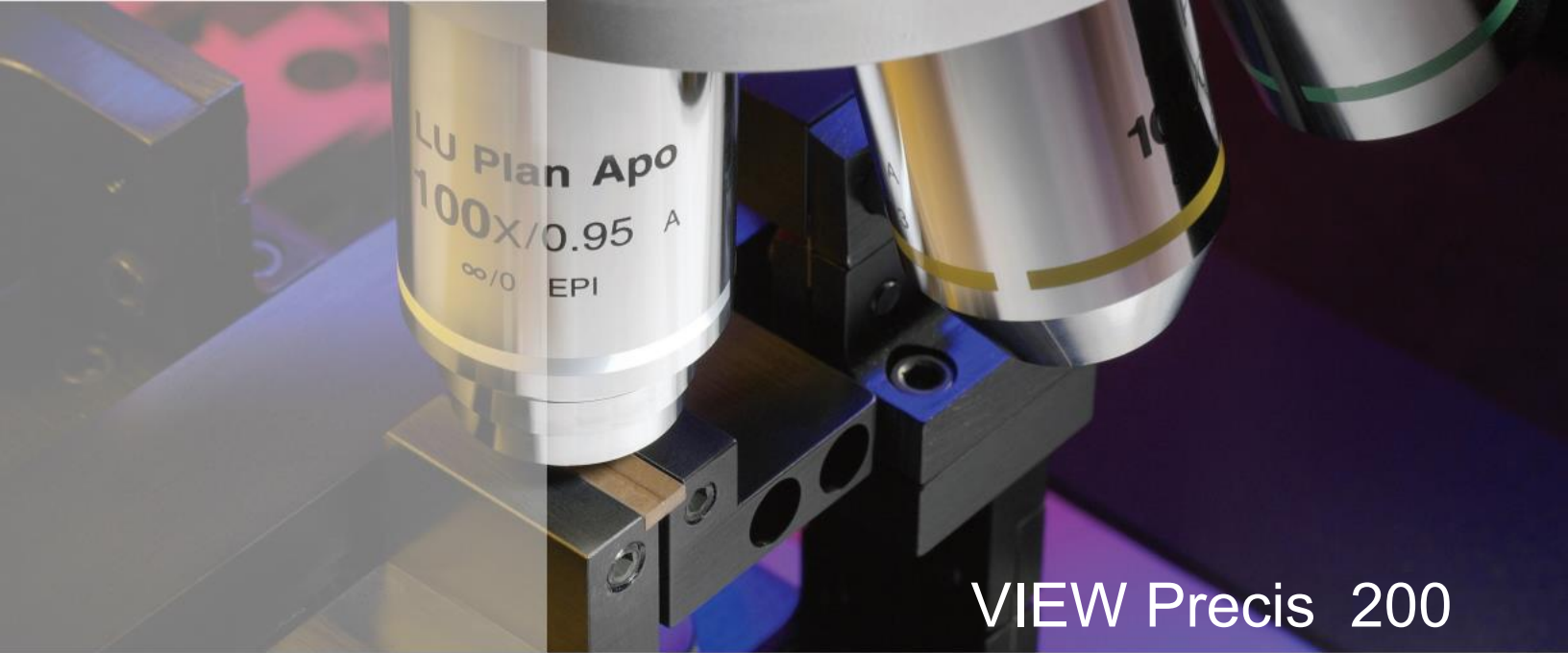




VIEW Precis 200

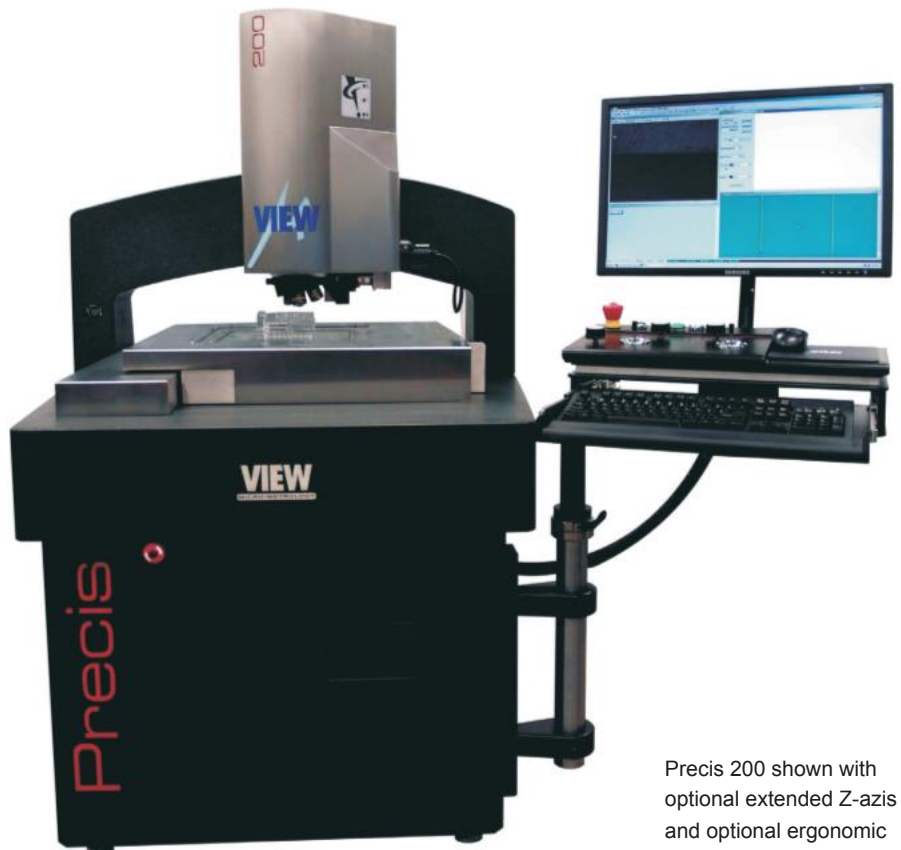
The VIEW Precis 200 from QVI is a high accuracy micro-metrology system for wafers, masks, MEMs, and HDD heads. The Precis combines precision stages, proven microscope optics, and a choice of three world-class metrology software packages to provide new levels of capability for process metrology.

The VIEW Precis delivers sub-micron field-of-view and point-to-point measurement accuracy on features as small as $0.65\ \mu\text{m}$.

- Dual Loop Servo Motion Control for precise and stable part translation
- Ergonomic control station and compact footprint
- Exclusive Mirco Focus Block provides rigid, repeatable focus motion

	X	Y	Z
Travel (mm)	200	200	5

Ultra high accuracy dimensional metrology system



Precis 200 shown with optional extended Z-axis and optional ergonomic workstation arm



Metrology Software:

- VIEW Metrology Software (VMS)
- Optional: Elements® metrology software
- Optional: Measure-X® metrology software

Available Optional Software Modules:

- Area Multi-Focus
- MeasureFit Plus
- SmartProfile 3D GD&T evaluation software
- Advanced image filtering, image stitching custom UI
- VMS Off-Line Workstation Software
- Digital IO

Uncrated: 1016 kg

Crated: 1316 kg

1600 x 1250 x 1700

	Standard	Optional
X,Y,Z Travel (mm)	200 x 200 x 5	200 x 200 x 100
XY Stage	Hand crafted, precision lapped compound stage	
Z Stage	Micro Focus Block™ microflexure focus assembly	Extended Z-axis motion with precision air bearing motion and linear motor drive
X,Y,Z Scale Resolution	0.01 μ m	
Stage Drive System	Rod drive DC servo X,Y motion, and rotary DC servo Z-axis motion	
Max Recommended Load	12 kg	
Imaging Optics	Microscope optics, including horizontal bright field/dark field illuminator, five-objective motorized lens turret, and camera back tube	
Front Lens (Field Interchangeable)	10X Bright Field 50X Long Working Distance, Bright Field	5X Bright Field or Bright Field/Dark Field 10X Bright Field or Bright Field/Dark Field 20X Long Working Distance, Bright Field or Bright Field/Dark Field 50X Long Working Distance, Bright Field or Bright Field/Dark Field 100X Long Working Distance, Bright Field or Bright Field/Dark Field
Metrology Camera	1.4 megapixel (1392 x 1040), 1/2-inch, digital, monochrome	2.0 megapixel (1628 x 1236), digital monochrome
Illumination	Full spectrum tungsten halogen coaxial surface light	Green LED transmitted light with auto N.A. stop
Sensor Options		Integrated photo spectrometer for photoresist and thin film thickness measurements
System Controller	Quad core processor, Windows® 7 Operating System and on-board networking and communication ports	
Controller Accessory Package	3-axis joystick for manual stage control, with E-stop and start buttons.	Single LCD flat panel display, computer keyboard and mouse Dual LCD flat panel displays, computer keyboard and mouse
Power Requirements	115/230 VAC, 50/60 Hz, 1-Phase, 700W	
Rated Environment	Temperature: 20°C $\pm$ 0.2°C Relative Humidity: 30% - 80% Vibration: ISO VC-B	Vibration: ISO VC-C for use of 150X objective lens
X,Y Linear Accuracy ^{1,2,3,4}	E: (0.25+2L/1000) μ m	
Z Linear Accuracy ^{1,2}	E: (0.25) μ m (with use of a 100x lens)	
Notes: All specifications apply to a thermally stable machine and a certified artifact.	¹ Maximum rate of temperature change: 0.5° C/Hour ² Maximum vertical temperature gradient: 1° C/Meter ³ At rated velocity with evenly distributed load of 5KG ⁴ X,Y linear accuracy artifact: QVI grid reticle (low expansion material) or QVI linescale in the standard measuring plane. Standard measuring plane is defined as within 25 mm of the worktable surface	